

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings of claims in the application:

LISTING OF CLAIMS:

1.(previously presented) A method of depositing an amorphous layer containing fluorine and carbon on a substrate in a vacuum, comprising:

depositing said amorphous layer via an ion gun adapted to eject ions in a form of a beam of accelerated ions created from at least one compound containing fluorine and carbon in gas or saturated vapor form fed to the ion gun,

wherein the amorphous layer containing fluorine and carbon is an exterior layer of an antireflection stack of an ophthalmic lens deposited on the substrate,

said exterior layer having a refractive index characteristic for fluorocarbons.

2.(canceled)

3.(previously presented) The method according to claim 1, wherein the ion gun is fed with the at least one compound containing fluorine and carbon mixed with oxygen or at least one rare gas.

4.(currently amended) The method according to claim 1, wherein the compound containing fluorine and carbon ~~ion gun is fed with the at least one compound which~~ comprises at least one aliphatic or cyclic fluorocarbon compound, at least one aliphatic or cyclic fluorinated hydrocarbon, or a mixture thereof.

5.(currently amended) The method according to claim 1 ~~4~~, wherein the compound containing fluorine and carbon comprises ~~the ion gun is fed with~~ perfluorocyclobutane ( $\text{c-C}_4\text{F}_8$ ) or a mixture with at least one other fluorocarbon compound comprising tetrafluoromethane ( $\text{CF}_4$ ) or hexafluoromethane ( $\text{C}_2\text{F}_6$ ), ~~or at least one rare gas.~~

6.(previously presented) The method according to claim 1, wherein the substrate is a plastics material substrate.

7.(previously presented) The method according to claim 1, further comprising fabricating the antireflection stack by the following steps:

- physical vapor-phase deposition (PVD) in a vacuum of three layers respectively having, from an interior toward the exterior, a layer having a first refractive index/a layer having a second refractive index/a layer having the first refractive index, type or a stack of  $\text{ZrO}_2/\text{SiO}_2/\text{ZrO}_2$ ; and

- depositing the exterior layer containing mostly fluorine and carbon using the ion gun,

wherein the second refractive index is lower than the first refractive index.

8.(previously presented) The method according to claim 7, wherein the PVD includes evaporation by electron bombardment of the material to be deposited.

9.(previously presented) The method according to claim 7, wherein each deposition step is carried out at a pressure less than or equal to  $10^{-2}$  Pa.

10.-17. (cancelled)

18.(previously presented) The method according to claim 8, wherein each deposition step is carried out at a pressure less than or equal to  $10^{-2}$  Pa.

19.(currently amended) The method according to claim 3 ~~17~~, further comprising fabricating an antireflection stack by the following steps:

- physical vapor-phase deposition (PVD) in a vacuum of three layers respectively having, from the interior toward

the exterior, a high refractive index/a low refractive index/a high refractive index, or  $\text{ZrO}_2/\text{SiO}_2/\text{ZrO}_2$ ;

- depositing the amorphous external layer containing mostly fluorine and carbon using the ion gun.

20.(cancelled)

21. (previously presented) The method according to claim 1, wherein the refractive index characteristic of fluorocarbons is 1.35-1.39.